

P. 01

SEP 16 2004

**REPLY UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1765**

PATENT
5298-06900/PM01027

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**For: REDUCING DEFECT FORMATION
WITHIN AN ETCIIED
SEMICONDUCTOR TOPOGRAPHY**

Atty. Dkt. No. 5298-06900

I hereby certify that this correspondence is being transmitted via facsimile or deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to:
Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313, on the date indicated below:

September 16, 2004
Date

Kevin L. Dattler

AMENDMENT; RESPONSE TO FINAL OFFICE ACTION DATED JULY 23, 2004

Dear Sir/ Madam:

This paper is submitted in response to the final Office Action dated July 23, 2004 to further highlight reasons why the application is in condition for allowance.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks begin on page 7 of this paper.